

IN THE TITLE:

Delete the title and insert therefor the following
new title:

METHOD OF MAKING LAMINA SPECIMEN

IN THE SPECIFICATION:

Paragraph beginning at line 8 of page 1, after the title, has been amended as follows:

In recent years, in various devices such as a semiconductor device and a display device, in order to realize an improvement in function, their structures have become fine smaller and complicated. Especially, an element or wiring forming each device becomes a laminated structure in which thin films of several-atom ~~level~~ levels have been overlapped, and a demand for observing that structure is high. For this reason, ~~such a technique becomes~~ one general technique is that the lamina is taken out by forming it by using a focused ion beam in a sample surface predetermined place, and it is observed by a high resolving power microscope such as transmission electron microscope.

Paragraph beginning at line 10 of page 2 has been amended as follows:

With a development of a device manufacturing technique, the structure of an object to be observed becomes fine. In order to observe this fine structure, although the transmission electron microscope is utilized, in order to observe the fine structure by the high resolving power microscope, there is shown the fact that, when performing a

lamina sample making for the observation, ~~an injury left in~~
damage to the lamina sample when the sputtering etching
working by the focused ion beam (FIB) has been performed is
made minimum and, at the same time, a shape confirmation of
the lamina sample is performed in a scanning electron
microscope (SEM) observation by an electron beam irradiation
scan.

Heading at line 5 of page 3 has been amended as follows:

Disclosure Summary of the Invention

**Paragraph beginning at line 23 of page 10 has been amended as
follows:**

Fig. 1 is one constitution example of a focused ion beam
composite apparatus ~~by~~ according to the present invention.

**Paragraph beginning at line 1 of page 11 has been amended as
follows:**

Fig. 2 is an explanatory view relating to an operation
of a sample stage used in the focused ion beam composite
apparatus ~~by~~ of the present invention.

Paragraph beginning at line 4 of page 11 has been amended as follows:

Fig. 3 is one embodiment of a method ~~by~~ according to the present invention.

Heading at line 9 of page 11 has been amended as follows:

~~Best Mode for Carrying Out~~ Detailed Description of the Invention

Paragraph beginning at line 12 of page 12 has been amended as follows:

Although the sample stage 7 has plural drive shafts and is adapted so as to be capable of moving the sample in a three-dimensional space with the sample 6 mounted, it becomes a structure in which, as shown in Fig. 2, with a 2nd plane 9 intersecting perpendicularly to a 1st plane 8 containing the 1st focused ion beam lens-barrel 1, the 2nd focused ion beam lens-barrel 2 and the inert ion beam lens-barrel 3 being made a reference, their intersecting angles are alterable. It suffices if an alterable range of the intersecting angles is at least ± 1 degree. This is a slant angle provided in order to stand up a side wall of the sample perpendicularly to the sample surface. If it can be experimentally slanted more than an angle of this degree, it is possible to ~~achieve an object.~~

~~That is, it is possible to~~ correct a slant of a side wall face of the sample.

Paragraph beginning at line 14 of page 14 has been amended as follows:

In Fig. 3, there is explained one embodiment of a method according to ~~by~~ the present invention.